## **REMARKS**

## General Remarks

Applicant has carefully studied the outstanding Office Action in the present application. The present response is intended to be fully responsive to all points of rejection raised by the Examiner and is believed to place the application in condition for allowance. Favorable reconsideration and allowance of the application are respectfully requested.

Claims 1-16 are pending in the application. Claims 1 and 9 are amended. Claims 2-8 and 10-16 are cancelled without prejudice. Support for the amendments to claims 1 and 9 is found in the specification in paragraphs [0025]-[0028] of the Patent Application Publication, *inter alia*. New claims 17-34 are added.

Support for new claims 17 - 34 is found in the specification as follows:

Support for new claims 17 and 27 is found in the specification in paragraphs [0025]-[0026] of the Patent Application Publication, *inter alia*.

Support for new claims 18 and 28 is found in the specification in paragraph [0025] of the Patent Application, *inter alia*.

Support for new claims 19 and 29 is found in the specification in paragraph [0388] of the Patent Application Publication, *inter alia*.

Support for new claims 20 and 30 is found in the specification in paragraph [0389] of the Patent Application, *inter alia*.

Support for new claims 21 and 31 is found in the specification in paragraph [0026] of the Patent Application, *inter alia*.

Support for new claims 22 and 32 is found in the specification in paragraphs [0408]-[0412] of the Patent Application Publication, *inter alia*.

Support for new claims 23 and 33 is found in the specification in paragraph [0414] of the Patent Application, *inter alia*.

Support for new claim 24 is found in the specification in paragraph [0027] of the Patent Application Publication, *inter alia*.

Support for new claim 25 is found in the specification in paragraph [0028] of the Patent Application Publication, *inter alia*.

Support for new claims 26 and 34 is found in the specification in paragraphs [0214]- [0217] of the Patent Application Publication, *inter alia*.

## Claims Rejections

Claims 1-16 stand rejected under 35 U.S.C. 102(e) as being anticipated by Meisberger et al. (5,578,821).

Meisberger et al. shows and describes an electron beam inspection system and method having two modes of operation: die-to-die and die-to-database. In die-to-database inspection the signal from one die derived from an electron microscope is compared with a signal that is derived from a database.

Applicant has amended claim 1 to further define the method of the present invention. Claim 1, as amended, recites, in relevant part, "said information defining said portion of interest comprising at least one of: binary Contour Element (CEL) data, identifying contour elements which correspond to borders between different regions in a pattern; color CEL data, identifying contour elements which correspond to borders between different regions in a pattern and identifying a type of region on either side of a CEL; morphological feature inspection triggers; and color defect inspection triggers." Similar amendments have been made to claim 9.

In addition to performing basic reference based inspection, the present invention, as recited in amended claims 1 and 9, also identifies specific information defining the portion of interest, where the information includes at least one of binary Contour Element (CEL) data, color CEL data, morphological feature inspection triggers and color defect inspection triggers.

Meisberger does not show or suggest an electrical circuitry inspection method or apparatus including, inter alia, inspecting an image of each of said at least one portion of interest, using a selected inspection task employing information defining said portion of interest where the information defining said portion of interest comprises at least one of: binary Contour Element (CEL) data, color CEL data, morphological feature inspection triggers and color defect inspection triggers, as recited in amended claims 1 and 9.

In view of the foregoing, Applicants respectfully request that the Examiner withdraw rejection of independent claims 1 and 9, and their respective dependent claims 17-26 and 27-34, each of which is patentable at least by virtue of its dependency from a patentable main claim.

## Conclusion and request for telephone interview

In view of the foregoing, this application is believed to be in order. Reconsideration and allowance of this application are respectfully solicited. If any points remain in issue which the Examiner feels may be best resolved through a personal or telephone interview, the Examiner is kindly invited to contact the undersigned attorney at the telephone number listed below.

Respectfully submitted

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